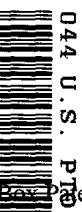


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6-14-01

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Docket No. 005643/CALB/L/B

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application  
Assistant Commissioner for Patents  
Washington, D.C. 20231

Re: Inventor(s): Sean Michael Seutter, Seshadri Ganguli, Mei Chang, Michael X. Yang, Ming Xi  
Title: Low-Resistivity Tungsten from High-Pressure Chemical Vapor Deposition  
Using Metal-Organic Precursors



Transmitted herewith is the patent application identified above, including:

- ☒ Specification, claims and abstract, totaling 25 pages.
- ☒ Drawings totaling 6 pages,    Formal ☒ Informal.
- ☒ Executed Declaration and Power of Attorney.
- ☒ Assignment of the invention to Applied Materials, Inc.
- ☒ Assignment Recordation Cover Sheet
- ☒ Information Disclosure Statement, PTO Form 1449 and ( ) References

FEE CALCULATION					
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	- 24	- 20 =	- 4	X \$18	\$ 72
Independent Claims	- 3	- 3 =	- 0	X \$80	\$ 0
Basic Filing Fee				\$710	\$710
TOTAL FEES					\$782

- ☒ The Commissioner is hereby authorized to charge \$782 to Deposit Account No. 50-1074
- ☒ The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074. A duplicate copy of this transmittal is enclosed.

☒ Please address all future correspondence to:  
**PATENT COUNSEL  
APPLIED MATERIALS, INC.  
Legal Affairs Department  
P.O.BOX 450A  
Santa Clara, CA. 95052**

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to Box Patent Application, Assistant Commissioner for Patents, Washington, D C 20231

Express Mail Receipt No EL661804590US  
Date of Deposit 6-12-01  
Signature Robert W. Mulcahy

Respectfully submitted,  
  
Robert W. Mulcahy  
Registration No. 25,436